This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently amended) Pressure sensor with an integrated structure (30, 30', 30") comprising:

a silicon die (11), having an upper edge (28), an inner face (23), and an outer face (24) on which piezoresistors (21) are mounted,

a support (33, 133, 233) having an upper surface (37, 137, 237), and a seat (34, 134, 234) suitable for containing the die (11),

a container (35) suitable for implementation in such a way as to put the die (11) in contact with the fluid the pressure of which has to be measured,

eharacterized in that wherein said die (11) is integrated in said seat (34, 134, 234), made in the thickness of the support (33, 133, 233).

- 2. (Currently amended) Pressure sensor with integrated structure (30, 30', 30") according to claim 1: characterized in that wherein the seat (34, 134, 234) passes through the support (33, 133, 233).
- 3. (Currently amended) Pressure sensor with integrated structure (30, 30', 30") according to elaims 1 and 2:claim 1 wherein eharacterized in that a step (43) is made on the inner surface of the container (35), enabling improved gluing of the support (33, 133, 233).
- 4. (Currently amended) Pressure sensor with integrated structure (30, 30', 30") according to any of the previous claims claim 1:

characterized in that wherein the upper edge (28) of the die (11) is substantially on the same plane as the upper surface (37, 137, 237) of the support (33, 133, 233).

5. (Currently amended) Pressure sensor with integrated structure (30, 30', 30") according to any of the previous claims claim 1:

characterized in that wherein the inner face (23) of the die (11) is in contact with the fluid the pressure of which has to be measured.

6. (Currently amended) Pressure sensor with integrated structure (30, 30', 30") according to any of the previous claimsclaim 1:

characterized in that wherein on the inner face (23) of the die (11), in contact with the fluid to be measured, is a layer of protection made from chromium, tantalum, silicon carbide alloys.

7. (Currently amended) Pressure sensor with integrated structure (30')-according to any of the previous claimsclaim 1:

characterized in that wherein in the vicinity of the upper surface (137) of the support (133), on the inside of the seat (134), a step (138) is made that runs along the edge of the seat (134) itself.

- 8. (Currently amended) Pressure sensor with integrated structure (30') according to claim 7: characterized in that wherein the die (11) is assembled in such a way that the upper edge (28) of the die (11) is in abutment with the step (138).
- 9. (Currently amended) Pressure sensor with integrated structure (30') according to elaims 7 and 8claim 7:

characterized in that wherein the surface of the part of the step (138), that is in contact with the upper edge (28) of the die (11), is less than the surface of the upper edge (28) itself.

10. (Currently amended) Pressure sensor with integrated structure (30") according to claims from 1 to 6claim 1:

eharacterized in that wherein in the vicinity of the lower surface (236) of the support (233), on the inside of the seat (234), a step (238) is made that runs along the edge of the seat (234) itself.

11. (Currently amended) Pressure sensor with integrated structure (30") according to claim 10:

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characterized in that wherein the upper edge (28) of the die (11) is substantially on the same plane as the upper surface (237) of the support (233).

12. (Currently amended) Pressure sensor with integrated structure (30") according to claims 10 and 11 claim 10:

characterized in that wherein the die (11) is assembled in such a way that its outer face (24) is in abutment with the step (238).